CORRECTION



Correction to: Development of a Vaporizer for Gradual Vaporization Control of Precursor Materials in the CVD Process

Tae Min Kim^{1,2} · Hyun Sik Sim² · Jae Wook Jeon¹

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Correction to:

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In the original publication of the article, the third author's affiliation was published incorrectly. The correct affiliation is given in this correction.

The original article has been corrected.

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☐ Jae Wook Jeon jwjeon@yurim.skku.ac.kr

- Department of Semiconductor and Display Engineering, Sungkyunkwan University, Seoul, Republic of Korea
- Memory Technology Innovation Team, Samsung Electronics Co., Ltd., Suwon-si, Republic of Korea

